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(54) **METHOD FOR MANUFACTURING MICROELECTROMECHANICAL COMBDRIVE DEVICE**

(75) Inventors: **Jennifer Scalf**, Pasadena, CA (US); **Satinderpal Pannu**, Berkeley, CA (US)

(73) Assignee: **Analog Devices, Inc.**, Norwood, MA (US)

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Primary Examiner—Minh Trinh
(74) *Attorney, Agent, or Firm*—JDI Patent; Joshua D. Isenberg

(57) **ABSTRACT**

Methods of making microelectromechanical combdrive devices are disclosed. The device may optionally be formed using three device layers. A moveable element and flexure may be formed from a first device layer. The second device layer may be attached to the first and a first set of comb teeth are formed from the second device layer. One or more comb teeth in the first set extend from a major surface of the moveable element. A third device layer is attached to the second device layer and a second set of comb teeth are formed from the third device layer. An alignment target is formed in the first device layer. Corresponding alignment holes are formed in the second or third device layers.

26 Claims, 4 Drawing Sheets